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	TO	Paul Schanoski	September 7, 2005
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(703) 413-3000 (703) 413-2220 FACSIMILE	FROM	Vincent K. Shier, Ph.D.	0160-0193-0 PCT
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OBLONPAT@OBLON.COM		703-412-6461	09/463,961
PATENT, TRADEMARK AND COPYRIGHT LAW AND RELATED FEDERAL AND ITC LITIGATION	MEGGA	DIRECT PHONE #	YOUR REFERENCE
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WWW.OBLON.COM

Further to our telephone conversation, I enclose herewith copies of the documents filed on August 9, 2004. If I may be of further assistance to you, please do not hesitate to contact me.

Best Regards, Vincent K. Shier, Ph.D.

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DOCKET NO.: 0160-0193-0 PCT/hyc

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Hiroshi IKEDA, et al.

SERIAL NUMBER: 09/463,961

GROUP: 1754

FILED: March 9, 2000

EXAMINER: Wayne A. LANGEL

FOR: PROCESS AND APPARATUS FOR TREATING SEMICONDUCTOR

PRODUCTION EXHAUST GASES

REQUEST TO CORRECT TITLE OF INVENTION

MAIL STOP ISSUE FEE COMMISSIONER FOR PATENTS P.O. BOX 1450 ALEXANDRIA, VA 22313-1450

SIR:

In the matter of the above-identified application for patent, we hereby request correction of your records to reflect the correct title of the invention. The title of the invention should read as follows: PROCESS AND APPARATUS FOR TREATING SEMICONDUCTOR PRODUCTION EXHAUST GASES.

Respectfully Submitted,

OBLON, SPIVAK, McCLELLAND, MAIER & NEUSTADT, P.C. Norman F. Oblon

Vincent K. Shier, Ph.D. Registration No. 50,552

Customer Number

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Tel. (703) 413-3000 Pax. (703) 413-2220 (OSMMN 05/04)

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Respectfully Submitted,

OBLON, SPIVAK, McCLELLAND, MAIER & NEUSTADT, P.C. Norman F. Oblon

Vincent K. Shier, Ph.D. Registration No. 50,552

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